

Package, Assembly and Thermal Challenges for Future Microprocessors

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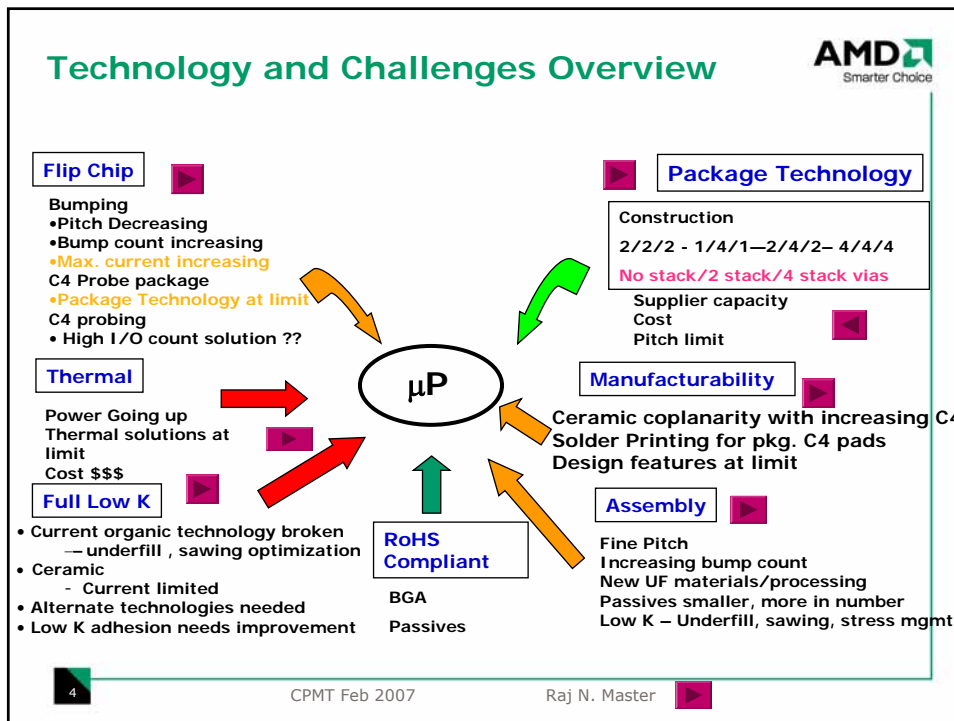
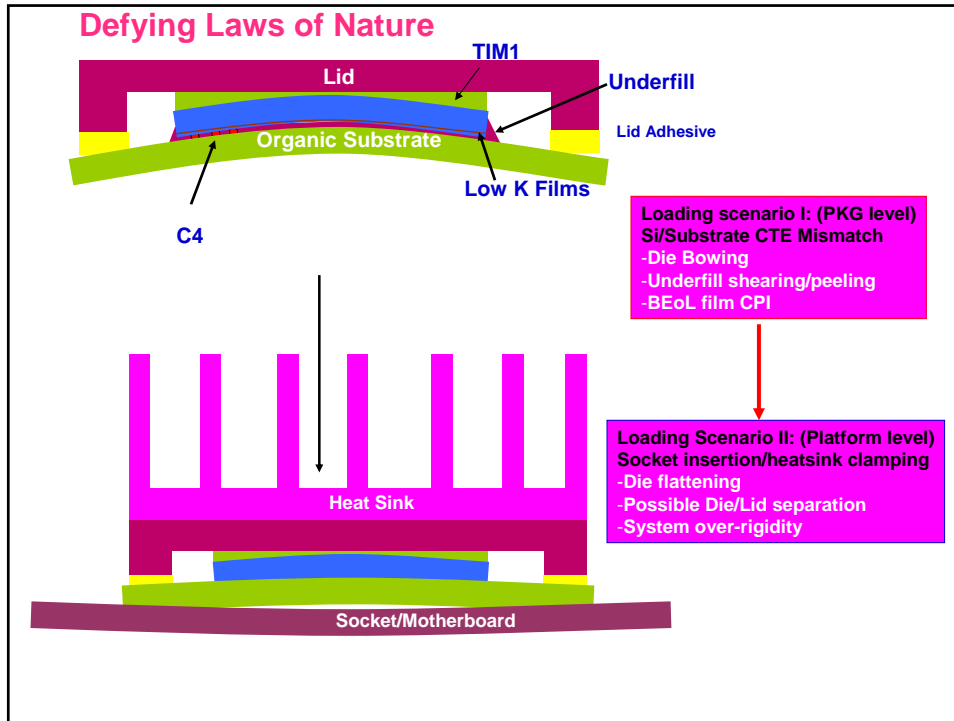
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Scope

- Flip Chip
- Package Technology and Manufacturability
- Assembly Technology
- Thermal
- Low K Challenges

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Flip Chip Challenges

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Pitch Decreasing from 350 μ ---> 150 μ --> ??

No. of bumps increasing ---> 5 – 10 K per die

- **Bumping Choice**
 - Electroplating --- Uniformity, extendibility, low defect rate
 - Screen printing --- Limited by Solder paste, stencil printing, voids
- **Current Carrying capability**
 - Current Density increasing -> limit pitch decrease
 - Bump and die at UBM via opening
- **Joule Heating significant**
- **Choice of Solder**
 - Eutectic Solder not suitable for EM
 - High Lead solders should be used

Alternate bumping/interconnection technologies required

- Bump less
- Pillar bumping
- Compliant springs, Nano links

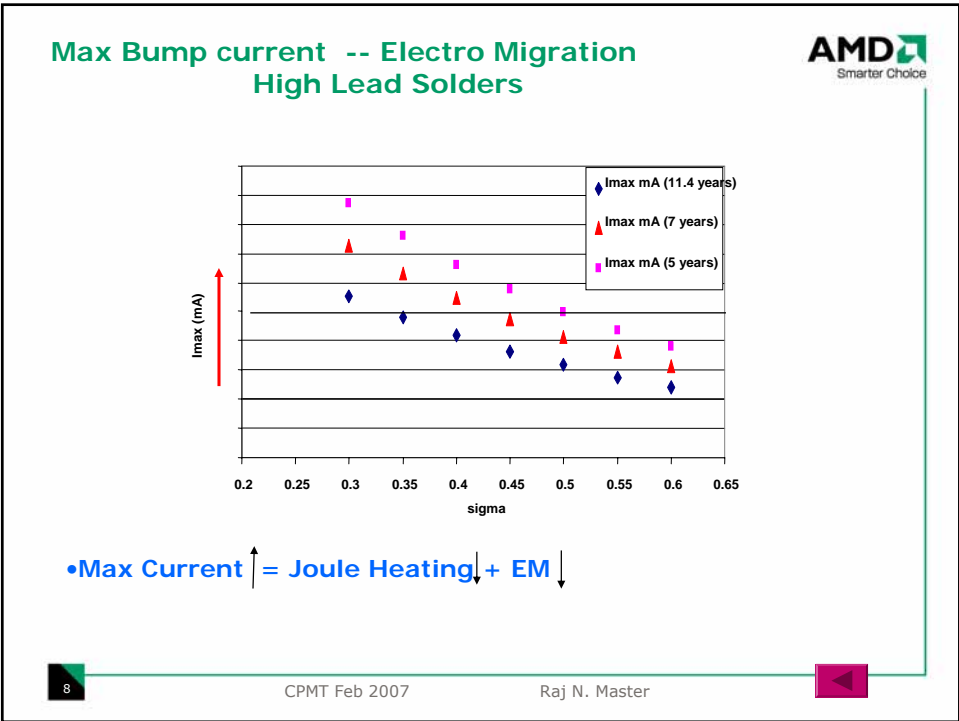
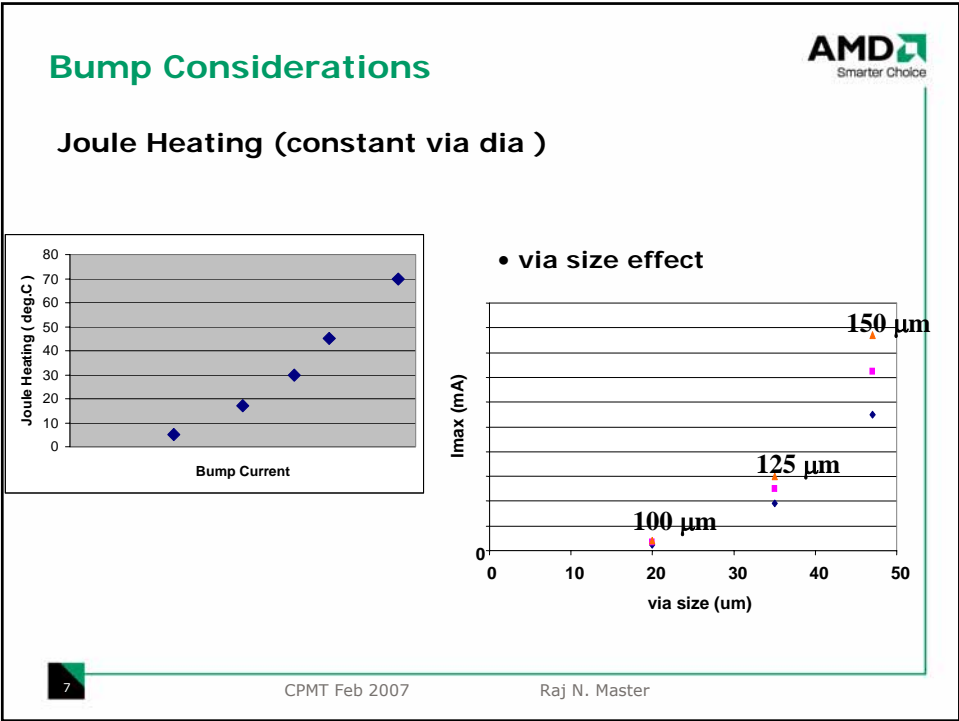
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Bump Geometry


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Figure 11 - A C4 Bump After Reflow

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Package Choice Criterion



Electrical Performance


Cost

Consistent supply of packages

Reliability

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Packaging Choices



Reliability

- Board Level
- C4

Board Level

- Organic ----- CTE = 18
- Solder Columns for ceramic
- High TCE Ceramic ----- CTE = 12 (Single Source)

C4

- Organic

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Package Selection

Ceramic

Advantages

- Mature Technology
- Multiple mature suppliers
- Higher moisture resistance
- Closer TCE match to Si
 - Low K
 - Large die
- Higher mechanical strength
 - Thermal solutions with higher load
- Higher reliability

Disadvantages

- Performance << organic
 - Mo vs. Cu conductor
 - Higher dielectric constant
- Pitch limited to 200 m at best for high volume
- Cost has matured

AMD Smarter Choice

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Package Selection

Organic

Advantages

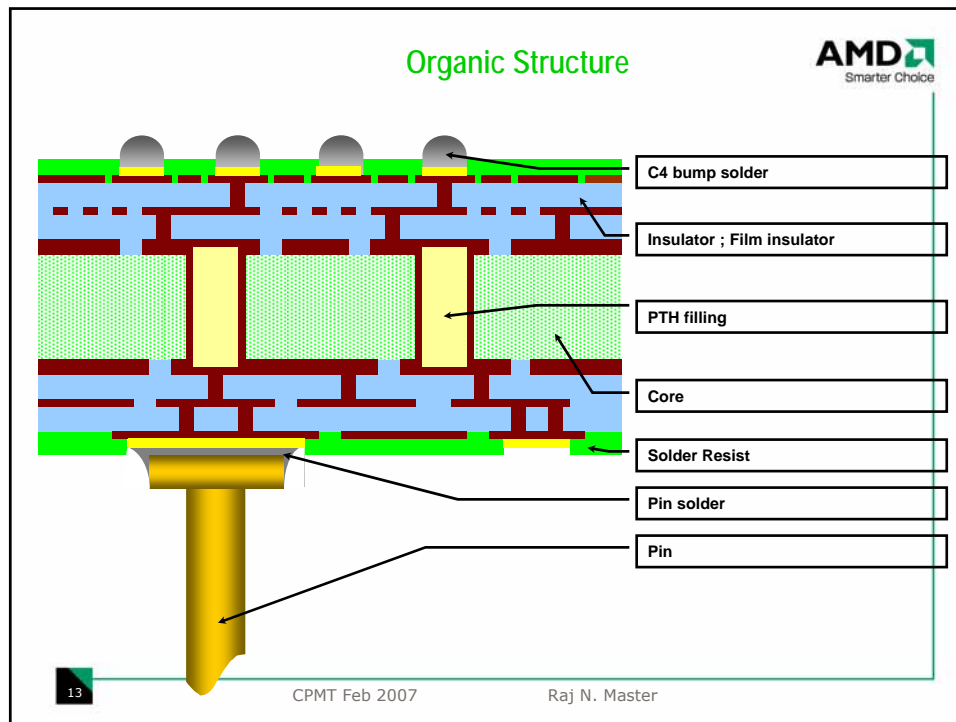
- Higher Performance
 - Copper conductors
 - Lower dielectric constant
- Cost cheaper than ceramic
- Design ground rules advanced and more manufacturable for higher performance designs
- Multiple reliable Suppliers

Disadvantages

- Moisture sensitivity
 - Lead free
- High TCE mismatch
 - Low k
 - Large die
- Sensitivity of assembly processes to surface conditions
- Lower mechanical strength
- Lower reliability

AMD Smarter Choice

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The slide is titled 'Package Challenges' and lists several key challenges in the industry. The AMD logo and 'Smarter Choice' tagline are in the top right corner. A small '14' is in the bottom left corner. The text 'CPMT Feb 2007' and 'Raj N. Master' is at the bottom.


Package Challenges

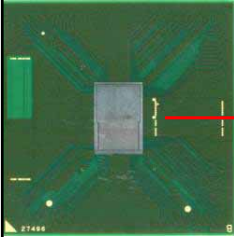
AMD Smarter Choice

- **Increased functionality and larger die**
 - **Finer Pitch**
 - Ceramic 200 μ
 - Organic 180 – 150 μ
 - **Larger body sizes to route**
 - Ceramic Finer features not manufacturable
 - Organic Finer features possible
requires material and process changes
- **Need for increased decoupling capacitance**
 - Higher cost Larger body size
 - Embedded capacitance breakthrough needed
- **Suppliers have different material sets**

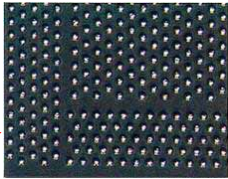
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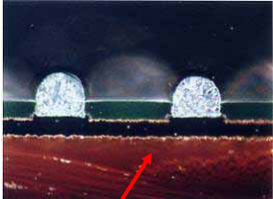
Package Complexity@ fine pitch



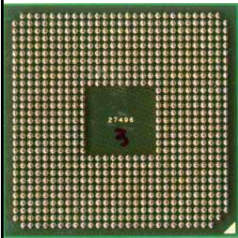


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Solder Printing



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Printing solder at fine pitch approaching limit
Jetting ??
Plating ??
Ball Attach???

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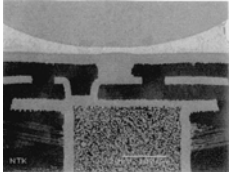
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Key challenges

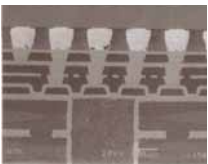


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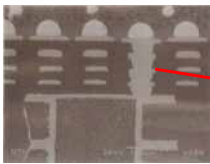
Unstack

4/4/4

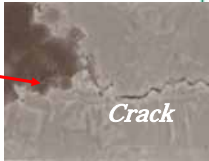


3 stack

4/4/4

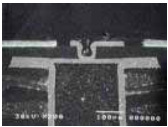
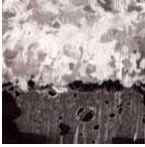


4 stack



Crack

- Build up materials
 - TCE
 - Temperature resistance for the solders used
- PTH material
 - TCE... excessive z motion can cause delamination cracking





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Package Manufacturing Challenges



Fine Pitch and Large no. of I/O require


- **Finer features**
 - Body Size
 - Routing
- **Drives substrate manufacturing to limit**
- **New Manufacturing processes required**

- **Cost pressures make it difficult**

- **Embedded capacitance????**


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Package Design Challenges



Core	Current rules (um)	Future rules (um)	Impact
min PTH diameter	300	200	Finer drill & thin core
min PTH pitch	600	400	Finer drill & thin core
Line width on core	90	50	New core patterning
max # of core Cu layers	4	6	New process
Build up			
Micro Via diameter	85	50	Need UV laser
Fine line/space	20/20	15/15	New dry film/pattern process
# of cu layers	2	4	Reliability/cost/capacity
Stacked vias	3	4	Reliability risk
Solder mask opening	90	60	New s-mask/Higher resolution

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Assembly

Chip Placement

Finer pitch drives higher accuracy

- Slows down UPH


Large die and finer pitch

- Stringent bump and package co planarity

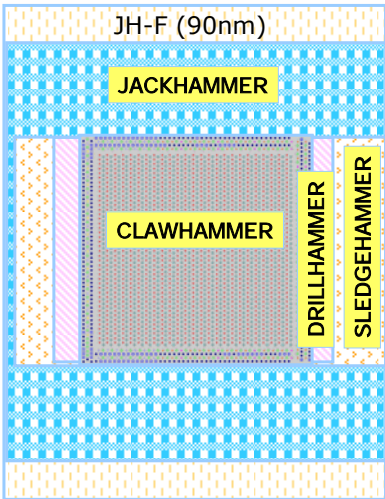
New fluxes required

- Low residue for larger area
- Compatibility with under fills
- Oxide removal

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Die footprints..... Die and Bump counts getting larger




CH	7.98 x 8.71	2821
DH	9.71 x 8.59	3490
SH	12.89 x 8.75	4676
JH	13.1 x 15.5	8876
JH	13.1 x 17.5	10000

What will they think next!!!!!!

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Assembly



UF materials

- **Finer particle size for lower standoff as pitch decreases**
 - Solids loading decreases due to high surface area
 - Effects physical and mechanical properties
- **Optimized physical / mechanical properties**
 - Large die
 - Low K

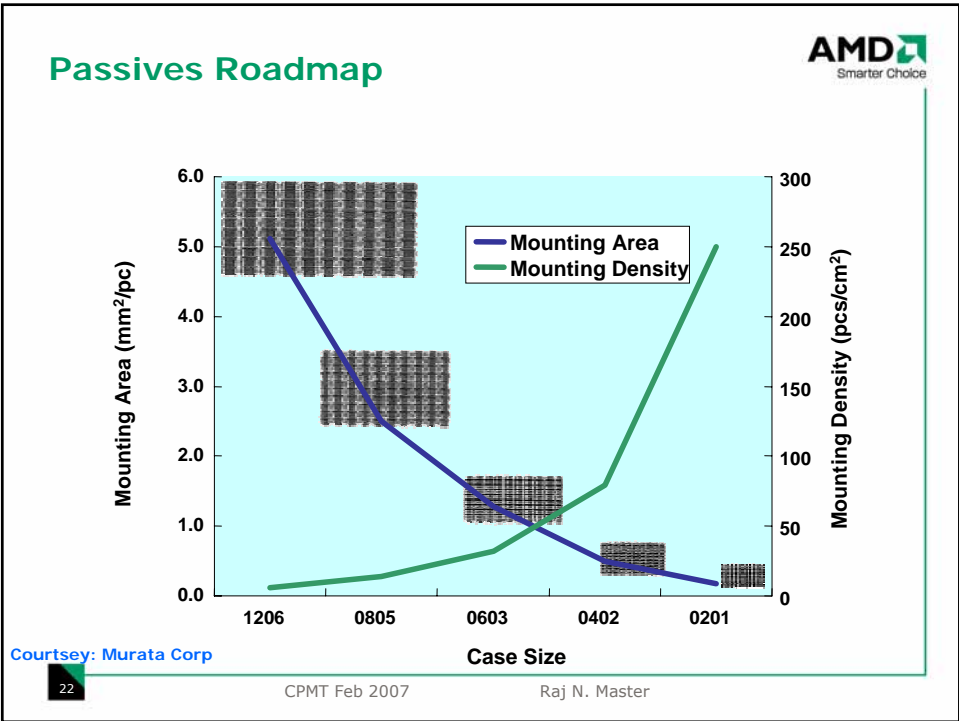
UF processes

- **Finer P.S.D. slows down the conventional UF dispense**
- **Sensitivity to Solder mask surfaces increases**
- **New approaches for high volume manufacturing??**
 - Novel dispensing methods
 - Jetting
 - Multiple needles (5 -10 simultaneously)
 - No Flow UF ??
 - Wafer applied UF ??
- **Defects become more critical**


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Assembly



Passives attachment

- Numbers are increasing

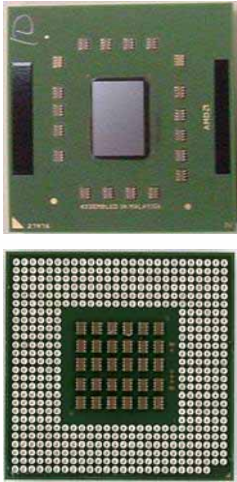
Evolution


- SMT
- Multi terminal LLA, IDC
- Resistors
- Smaller sizes

Processes and defects


- Dispensing at limit....
Shorting, tombstoning, unbalanced fillets
- Printing
- ???

Embedded Package capacitance required

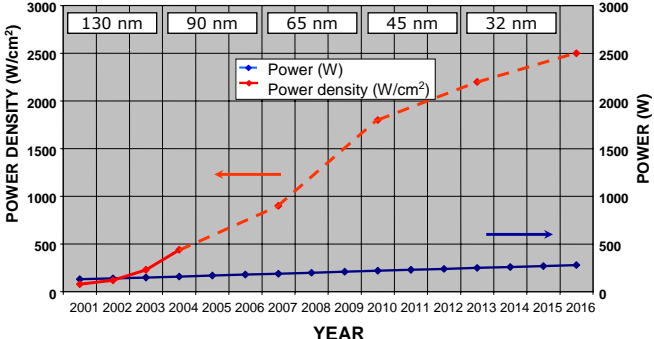


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Thermal Issues





The 2002 ITRS says power increases gradually and die size remains constant at ~300 mm²: **But that's not the whole story...**



Year	Power (W)	Power density (W/cm ²)
2001	~100	~100
2002	~150	~200
2003	~200	~400
2004	~250	~700
2005	~300	~1100
2006	~350	~1600
2007	~400	~2200
2008	~450	~2800
2009	~500	~3500
2010	~550	~4200
2011	~600	~5000
2012	~650	~5800
2013	~700	~6600
2014	~750	~7400
2015	~800	~8200
2016	~850	~9000


... because the power dissipating area (core) continues to shrink!
(and as # of transistors increases, so does total switching current required!)


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Thermal Interface Materials

- **Traditional Curable Grease / PCM with Solid Fillers**
 - Ease of Application
 - Understood Reliability
 - Low Cost
 - Thermal Resistance does not Meet Future Requirements
- **Solder**
 - Low Thermal Resistance
 - Best Thermal Resistance Uniformity
 - Concerns with Temperature and Power Cycling Reliability
 - Surface Preparation and Added Manufacturing Steps
- **Liquid Metal Hybrids**
 - Low Thermal Resistance
 - Needs Containment
 - Poor Understanding of Reliability
- **Materials Under Research**
 - Carbon Nanotubes
 - Graphite Derivatives


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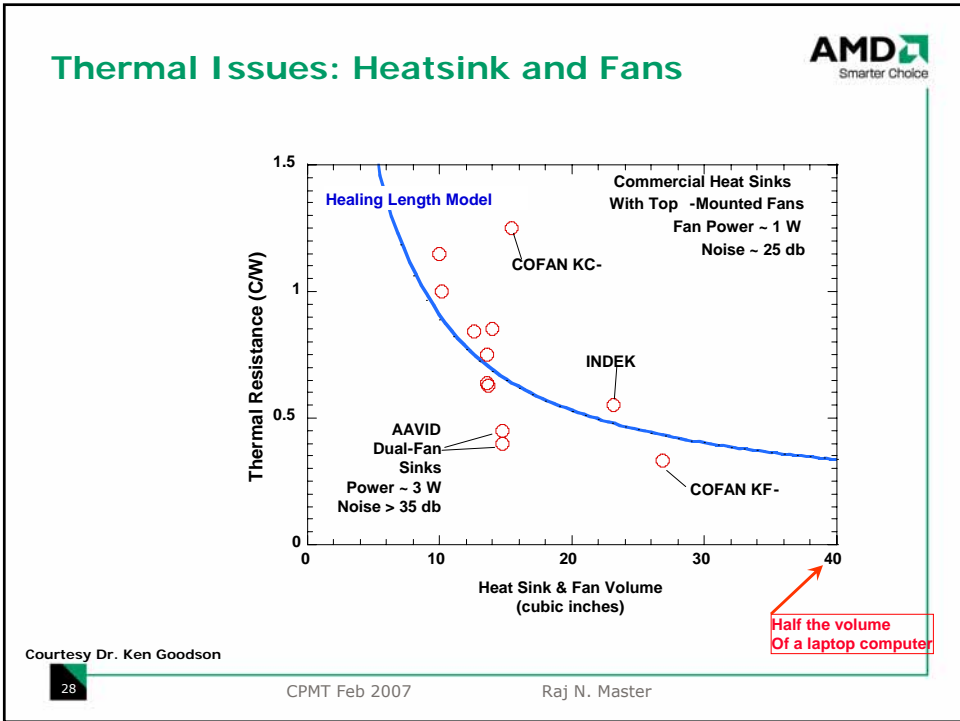
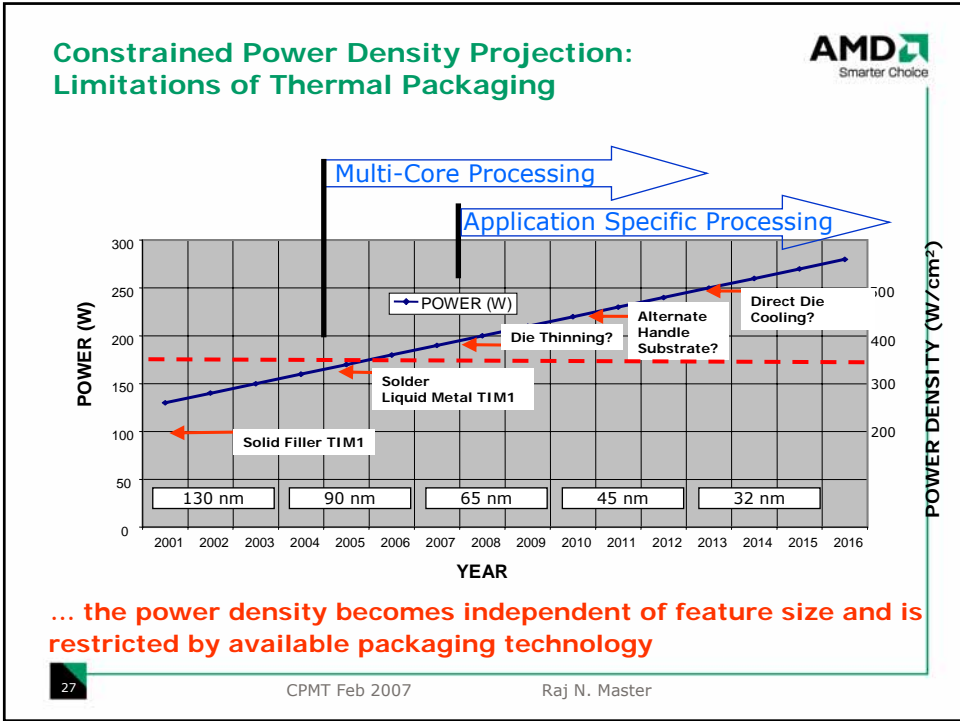


Thermal Issues: Solutions

Power density cannot continue to increase at this rate, but in the near-term we need to address up to 500 W/cm² (Hotspot cooling)!

- **Very thin die to reduce thermal resistance through the Si**
- **New thermal interface materials (TIMs)**
 - High thermal conductivity metallic fillers
 - Phase change filler materials with high heat of transformation
 - Low contact resistance (wetting on difficult surfaces)
 - High elasticity to account for mechanical stress
- **Refined surfaces at thermal interfaces**
 - Polished to reduce asperities and contact resistance
 - Reactive to improve wettability of TIMs
- **New heat spreader materials**
 - Maybe diamond finally has a chance
- **New cooling technologies**
 - Heat sinks and fans losing efficiency (increasing volume/watt removed)
 - Liquid cooling with miniaturized pumping systems
 - Need to bring cooling technology directly to the die

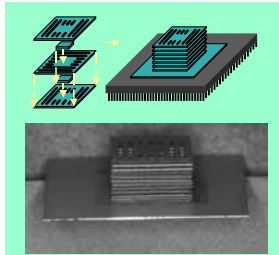
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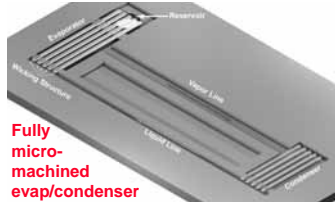
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Thermal Issues: Direct die cooling (liquid)


Micromachined Capillary Evaporator Designs



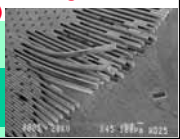
Multilayer micromachined evaporator increases capillary pressure (U. Maryland)



Fully micro-machined evap/condenser (UC Berkeley)



Single-layer optimized wicking structure (Sandia / Texas A&M)



Courtesy Dr. Ken Goodson
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Low-K Overview

Ceramic
Organic

Package Alumina (Std)

- Better CTE match for full Low K
 - Reliability data supports
 - Fine pitch problem
 - Performance marginal
- Glass – Ceramic (LTCC) / Cu
 - Not ready for high volume
 - Cost= 1.5-2X current

Low K

Package Organic

- Current organic technology broken for full Low K
 - Die adhesion improvement Key
 - Low CTE package required
 - No successful approaches
- Cost=1.5-2X current package

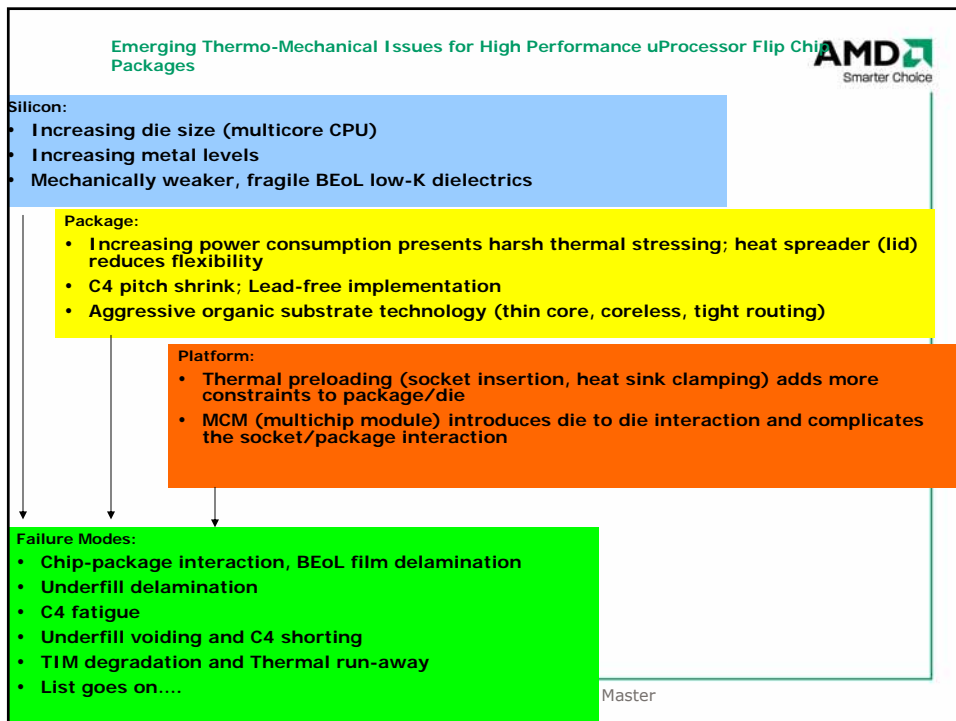
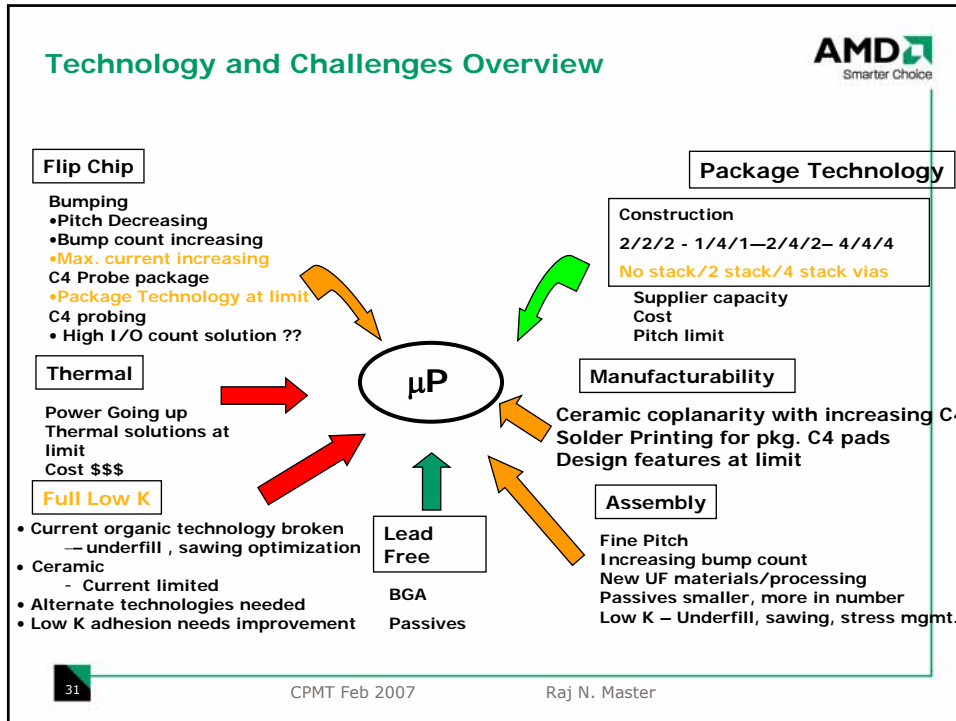
Assembly

- Current state-of-the-art 150 μ
- Laser saw possible


Assembly

- Laser saw needed
- Full low K drives material and process solutions
 - stress management

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Skill Set Required



- Material Science
- Chemistry
- Physics
- Mechanical Engineering
- Thermal Engineering
- Fluid Dynamics
- Fracture Mechanics
- Modeling
- Analytical techniques
- Surface Science
- Adhesion Science
- Metallurgical Engineering
- Mathematics
- Electrical Engineering

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Summary



- **Approaching limit on many technology fronts**
- **Conflicting direction**
- **Thinking outside the box required**
- **Collaboration between Users, Suppliers and Academia**

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